IN THE CLAIMS

Please amend Claim 13 as shown in marked-up form:

1. (Previously Presented) A device for the inspection of one or more a rotating surface (8) of a wafer (13), which device includes at least one light source (1), and a beam splitter (4) for splitting a light beam (2) that is emitted by said source into at least one reference beam (6) that is applied to a detector (16) and at least one measuring beam (5) that is applied to the surface (surfaces), the at least one measuring beam (5) containing at least one component in the direction of movement (U) of the relevant surface (8) or in the opposite direction, and the light (15) that is reflected by the surface (8) having, at least upon detection of a defect (14) on the surface (8), a frequency (v') that has been shifted relative to the at least one measuring beam (5) and that the at least one reference beam (6) can be superposed thereon, characterized in that the device includes an evaluation unit (29) for determining the velocity (v) of a defect (14) on the surface (8) from the shifted frequency (v') and from this velocity the position of the defect on the surface (8).

2. (Original) A device as claimed in claim 1, characterized in that the detector (16) has exactly one entrance window that is

capable of detecting the superposition of the reference beam (6) and the reflected light (15).

3. (Previously Presented) A device as claimed in claim 1, characterized in that there are provided two detectors (16; 17), the reference beam (6) being detectable by a first detector whereas the superposition of the reference beam (6) and the light (15) can be detected by a second detector.

4. (Previously Presented) A device as claimed in claim 1, characterized in that the superposition of the reference beam (6) and the reflected light (15) is formed in an optical beam path and that the superposition image thus obtained can be projected into an entrance window of a detector (16).

5. (Previously Presented) A device as claimed in claim 1, characterized in that the input signal formed by the superposition of the reference beam (6) and the reflected light (15) can be electronically evaluated and that a frequency shift (v-v´) of the reflected light (15) can be determined therefrom.

6. (Previously Presented) A device as claimed in claim 1, characterized in that the velocity of rotation (v) of a rotating

defect (14) can be calculated from to the frequency shift (v-v') by way of the Doppler formula.

7. (Previously Presented) A device as claimed in claim 6, characterized in that a radial position (r) of the defect (14) can be calculated from the velocity (v) of the defect (14) while a circular frequency (ω) of the rotation of the surface (8) is known.

8. (Previously Presented) A device as claimed in claim 1, characterized in that a moving surface (8) is associated with a device for detecting its instantaneous orientation.

9. (Original) A device as claimed in claim 7, characterized in that the surface (8) is rotatable in the plane in which its major axis extends and that the device enables detection of the angle of rotation.

10. (Previously Presented) A device as claimed in claim 4, characterized in that the position of a defect (14) on the inspected surface relative to a scale can be determined from the signal detected by the detector (16; 17).

11. (Previously Presented) A device as claimed in claim 1, characterized in that the surface (8) to be inspected can move in a rotational as well as in a translational mode.

12. (Cancelled)

13. (Previously Presented) A method for the inspection of one or more moving surfaces, where a light beam that is emitted by a light source, is split by means of a beam splitter into at least one reference beam that is applied to a detector and a measuring beam that is applied to the surface, the measuring beam containing at least one component in the direction of movement of the relevant surface or in the opposite direction, the light that is reflected by the surface having, at least upon detection of a defect on the surface, a frequency that has been shifted relative to the measuring beam, and the at least one reference beam being superposed on said reflected light, characterized in that the speed of a defect on the surface is determined from the superposed signal formed from the at least one reference beam and the reflected light, and that the position of the defect on the surface is determined therefrom.

14. (Previously Presented) An evaluation unit (29) for evaluating at least one electrical input signal which contains an alternating voltage component, the evaluation unit storing a computer program, that is, notably a program for carrying out the method in conformity with claim 13, characterized in that the computer program determines the frequency of the input signal from an alternating voltage component thereof, compares this frequency with a reference and calculates therefrom, by way of the Doppler formula, the velocity that corresponds to the frequency difference between said signals.